



Attorney Docket No. 04216/LH

**IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE**

Applicant(s): Yoshinori IKETAKI

Serial No. : 10/821,474

Filed : April 8, 2004

For : MICROSCOPE AND ITS OPTICAL  
CONTROLLING METHOD

Art Unit :

**CUSTOMER NO.: 01933**

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. BOX 1450  
Alexandria, VA 22313-1450

Att: MS - MISSING PARTS

S I R :

**Amendments to the Specification** are described on page 2 of this paper.

**Remarks** begin on page 3 of this paper.

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class mail in an envelope addressed to: Mail Stop Missing Parts, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date noted below.

A handwritten signature in black ink that reads "Sharon Portnoy".

Dated: August 12, 2004

In the event that this Paper is late filed, and the necessary petition for extension of time is not filed concurrently herewith, please consider this as a Petition for the requisite extension of time, and to the extent not tendered by credit card (Form PTO-2038 attached hereto), authorization to charge the extension fee, or any other fee required in connection with this Paper, to Account No. 06-1378.

Please delete the abstract and add the following new abstract:

Abstract

A microscope includes a first deflection device which deflects first light from a first light source that excites a molecule included in a specimen from the ground-state to a first electronically excited state, and a two dimensionally second deflecting device which deflects second light from a second light source to excite the molecule from the first exciting state to a second exciting state with a higher energy level. A combining device synthesizes the deflected first light and second light on the same optical axis or on a mutually parallel optical axis. A third deflection device deflects the synthesized first light and the second light simultaneously. Luminescence is detected by adjusting the optical axes of the first light to the third light by the first to third deflection device, and by overlapping part of these lights by a beam-condensing optical system and irradiating them on the specimen.